

Title (en)  
Vacuum pump mounting system

Title (de)  
Anordnung mit Vakuumpumpe

Title (fr)  
Dispositif de montage pour pompe à vide

Publication  
**EP 1933037 B1 20180905 (DE)**

Application  
**EP 07022563 A 20071121**

Priority  
DE 102006058672 A 20061213

Abstract (en)  
[origin: EP1933037A2] The arrangement has a vacuum chamber (1) with a chamber flange (3) and a vacuum pump (2) that has a high speed rotor and a pump flange (4) arranged in a rotor housing. It has a torque-resistant securing arrangement that connects the rotor housing to a torque sink. The torque-resistant securing arrangement contains a ring (11) enclosing the rotor housing.

IPC 8 full level  
**F04D 17/16** (2006.01); **F04D 19/04** (2006.01); **F04D 29/60** (2006.01)

CPC (source: EP)  
**F04D 19/04** (2013.01); **F04D 19/042** (2013.01); **F04D 29/601** (2013.01); **H01J 2237/16** (2013.01); **H01J 2237/1825** (2013.01)

Citation (examination)  
• US 2006024184 A1 20060202 - NAKAMURA FUSAO [JP], et al  
• JP S61294191 A 19861224 - SEIKO SEIKI KK, et al

Cited by  
EP2149710A3

Designated contracting state (EPC)  
AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HU IE IS IT LI LT LU LV MC MT NL PL PT RO SE SI SK TR

DOCDB simple family (publication)  
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DE 102006058672 B4 20160915

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